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TITLE: Method for measuring solid density and primary
particle size of slurry for chemical mechanical
polishing process using ultraviolet spectrometer

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ABSTRACTED-PUB-NO: KR2002054538A

BASIC-ABSTRACT:

NOVELTY - A method for measuring solid density and primary particle size of slurry is provided to measure solid density and primary particle size in a convenient and accurate manner within a short time period, while allowing slurry quality control to be easily performed.

DETAILED DESCRIPTION - A method for measuring solid density and primary particle size comprises the steps of transmitting ultraviolet ray to the slurry

made of deionized water, metal oxide fine powder and additives, measuring transmissivity, and comparing the measured transmissivity with a calibration curve. The step of transmitting ultraviolet ray to the slurry uses a cell(5) of quartz material having an ultraviolet transmission length of 0.1 to 2cm. The step of measuring transmissivity uses a light source having a wavelength of 300 to 1100nm. The calibration curve is made by using a slurry including a metal oxide having a size same as the size of the slurry.

CHOSEN-DRAWING: Dwg.1/10

TITLE-TERMS: METHOD MEASURE SOLID DENSITY PRIMARY PARTICLE SIZE
SLURRY CHEMICAL
MECHANICAL POLISH PROCESS ULTRAVIOLET SPECTROSCOPE

DERWENT-CLASS: S03

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